

VERITYSEM 200mm/300mm INTRODUCTION TO SEM

Who should attend?

This course is designed for those individuals in the semiconductor industry who require a general understanding of the Scanning Electron Microscope (SEM) of the VeritySEM 200mm/300mm system.

Course Benefits

Provide technical foundation necessary to work effectively with Applied Materials equipment. Provide understanding of equipment function, operation, and basic process application for Applied Materials equipment.

Course Objectives

- Identify and describe the purpose and function of the SEM imaging system.
- Describe the Working Principles and the creation of the Electron Beam.
- Describe the structure and operation of the Electron Gun.
- Describe the SEM AF concept for VeritySEM, delta Vacc, and DMD
- Describe the advanced functional description for the electron column and components using block diagrams
- Describe Column Performance Monitoring
- Describe Column Corrective Maintenance Activities
- Describe the Advanced Functional Description of the detector using Block Diagrams
- Describe the Advanced functional description of the Beam Deflection Module (BDM)

Registration Information

Prerequisites: *None*
Course Length: *1.5 Hours*
Course Type: *Web-based Training*
Course Number: *TRNWEB-155*

To enroll or for more information on our products and services, please call our registrar at one of the numbers below or go to www.appliedtraining.com.

- 1-800-468-8888, option 4 (United States)
- 1-512-272-0027 (International)

Computer System Requirements:

Attending this course requires a Windows 98, NT, 2000 or XP computer using Internet Explorer 5.5 or higher. 128MB RAM or higher and high-speed Internet access is also highly recommended. For the audio portion of the class, headsets or speakers and a sound card are required.